

RECEIVED  
CENTRAL FAX CENTER

DEC 20 2004

8270 Greensboro Drive, Suite 630  
McLean, VA 22102

Telephone 202.822.4554

Facsimile 202.478.1771

**Fax**

**To:** United States Patent and Trademark  
Office **From:** Jonathan A. Hack

---

**Fax:** 703.872.9306 **Pages:** 11 (including cover sheet)

---

**Phone:** **Date:** December 20, 2004

---

**Re:** U.S. Application No.: 10/085,753 **CC:**

---

**Urgent**  **For Review**  **Please Comment**  **Please Reply**  **Please Recycle**

---

**Comments:**

With respect to:

In Re the Application of: **TSUGA et al.** Group Art Unit: 1746  
U.S. Patent Application No.: 10/085,753 Examiner: Michael Kornakov  
Filed: February 28, 2002 Attorney Docket No.: TI-31620  
Title: METHOD AND DEVICE FOR REMOVING PARTICLES ON SEMICONDUCTOR  
WAFERS

Please find:

1. Petition For Extension of Time
2. Amendment in response to the Office Action dated June 18, 2004

**RECEIVED  
CENTRAL FAX CENTER**

**DEC 20 2004**

**PATENT**

Attorney Docket No. TI-31620

Application No.: 10/085,753

Customer No.: 23494

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:

**TSUGA et al.**

Application No.: 10/085,753

Filed: February 28, 2002

For: **METHOD AND DEVICE FOR  
REMOVING PARTICLES ON  
SEMICONDUCTOR WAFERS**

)

)

) Group Art Unit: 1746

)

) Examiner: Michael Kornakov

)

)

)

)

)

Assistant Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the Office Action dated June 18, 2004, the period for reply having been extended for three months, December 18 being a Saturday, by a request for extension of time filed concurrently herewith, please amend the application as follows:

**Amendments to the claims begin on page 2 of this paper.**

**Remarks begin on page 5 of this paper.**